

Semiconductor Industry Exhaust Management, POU Abatement Device, and Centralized Abatement Equipment

This PDC will provide detailed information on exhaust management, point-of-use abatement devices, and centralized abatement equipment in a semiconductor fab or similar operations. The determination of how to develop a process exhaust management strategy will be presented. The segregation and abatement of ammonia and abatement of fluorine are major exhaust management challenges that will be discussed. The design and operation of centralized wet scrubbers will be reviewed. The types of volatile organic compound (VOC) equipment will be explained. This PDC will be instructed with opportunities for the attendees to ask their specific questions. Handouts and ample opportunity to ask questions, discuss concerns and interact with instructors and classmates.